

Epitaxial Alkali-antimonide Photocathodes on Lattice-matched Substrates

Name: Pallavi Saha

Supervisor: Prof. Siddharth Karkare

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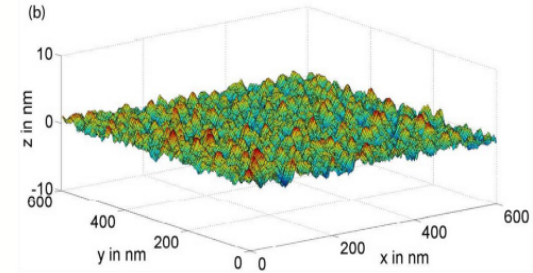
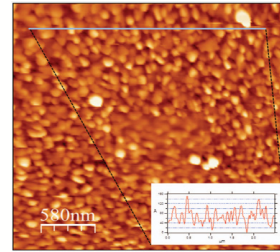
- Howard A. Padmore



Outline

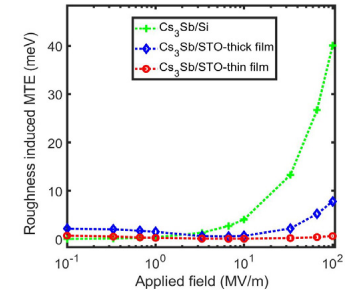
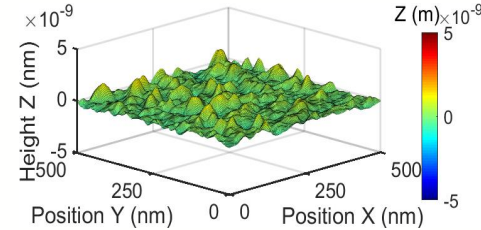
➤ Introduction

- Why alkali-antimonides?
- History of growths



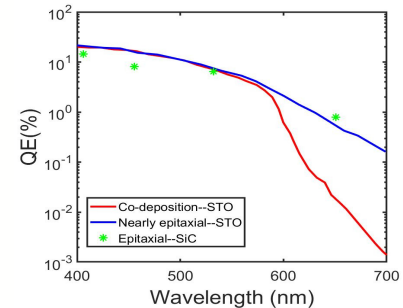
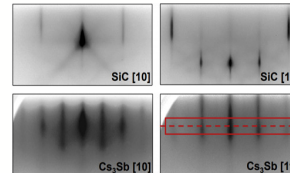
➤ Co-deposition on lattice-matched substrates

- AFM and KPFM data from Cs_3Sb/STO
- Roughness induced intrinsic emittance/ MTE



➤ Epitaxial efforts on alkali-antimonide photocathodes

➤ Conclusion and future steps



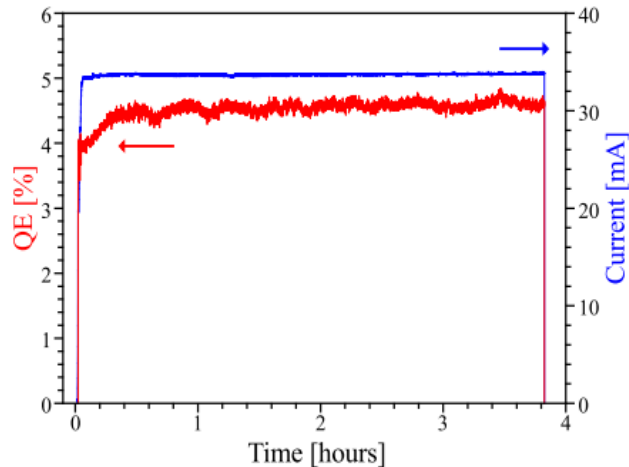


Why alkali-antimonides?

➤ High QE, long lifetimes

High current applications

- Energy Recovery Linacs
- Electron beam cooling

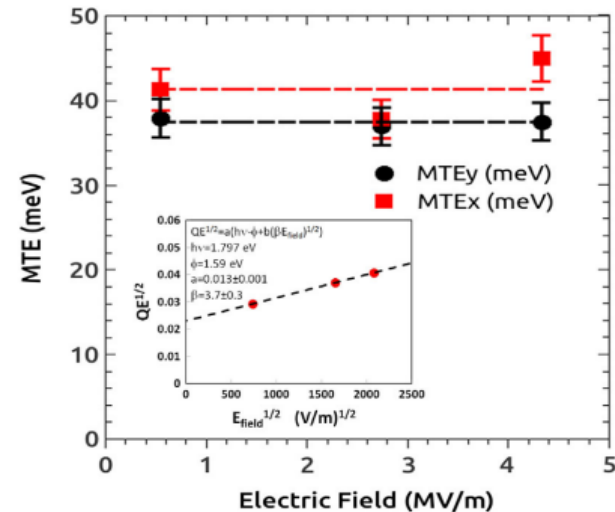


B. Dunham et. al., Appl. Phys. Lett. 102, 034105 (2013).

➤ Low MTE

Low emittance applications

- X-ray Free Electron Laser
- Ultrafast Electron Diffraction

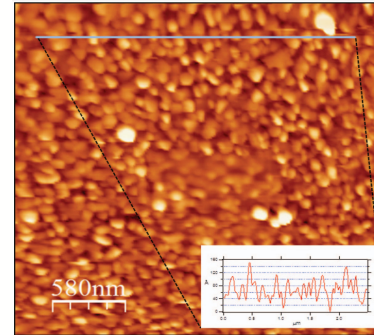


L. Cultrera et. al., PRAB. 18, 113401 (2015).



History of (bi)alkali-antimonides growths

➤ Sequential deposition technique

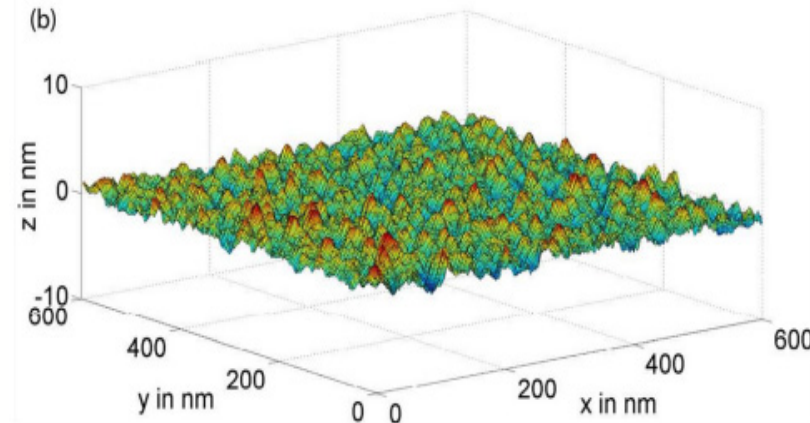


rms roughness ~
25 nm

S. Schubert et al., APL Mater. 1, 032119 (2013)

➤ Co- deposition technique

rms roughness ~ **0.6nm**

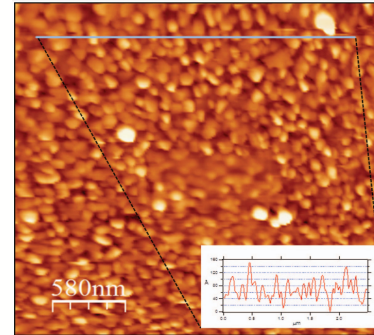


J. Feng et al., J. Appl. Phys. 121, 044904 (2017).



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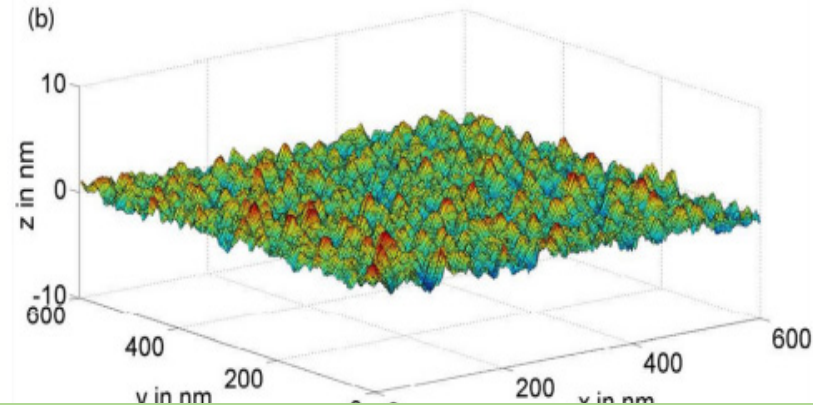


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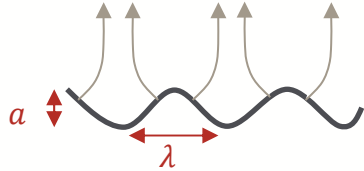


How does roughness impact MTE? How to reduce roughness?



Impact of Roughness on MTE

Physical roughness



$$MTE_{field} = \frac{\pi^2 a^2 E_0 e}{2\lambda}$$

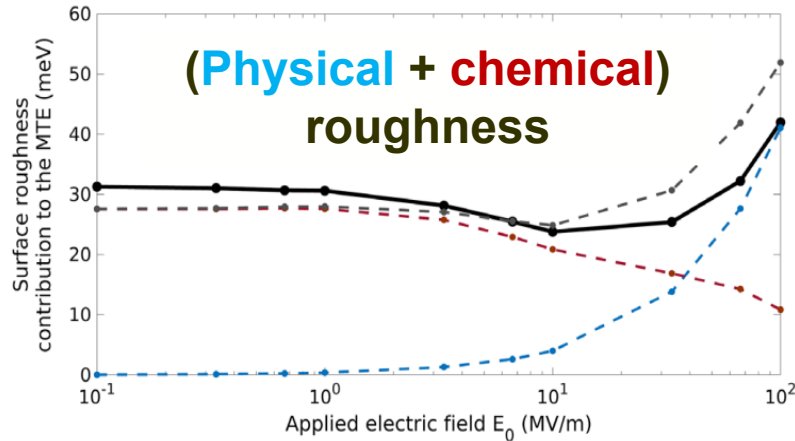
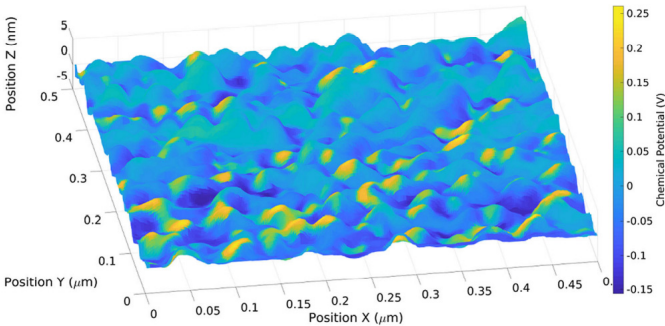
J. Feng et al., J. Appl. Phys. 121, 044904 (2017).

Chemical roughness

$$MTE_{wf} = \frac{\pi^2 h^2 e}{4\sqrt{2} a E_0}$$

S. Karkare and I.V. Bazarov, Phys. Rev Applied, 4, 024015 (2015).

Non-trivial, non-monotonic dependence on accelerating field gradients!

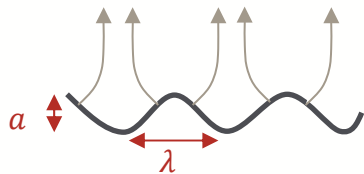


G. Gevorkyan et al. Phys. Rev. ST- Accel and Beams, 21, 093401 (2018)



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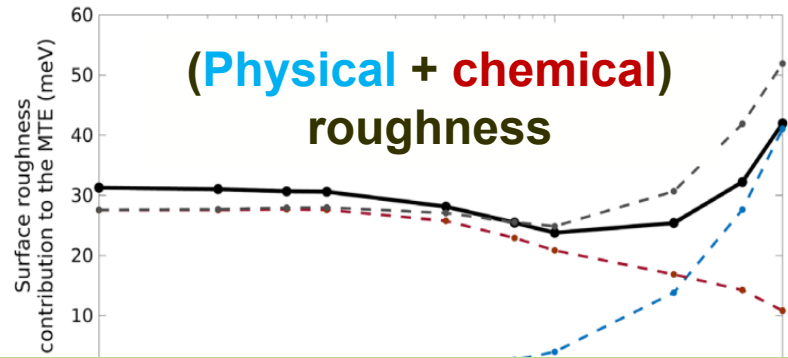
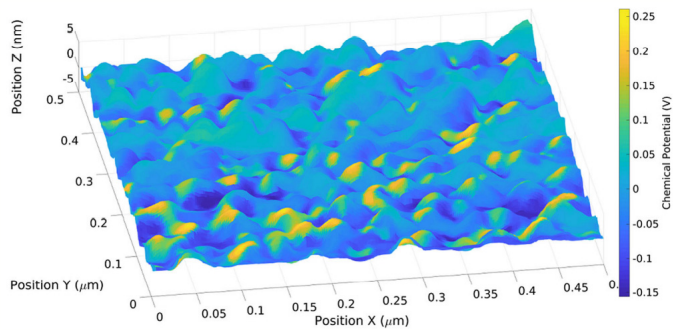
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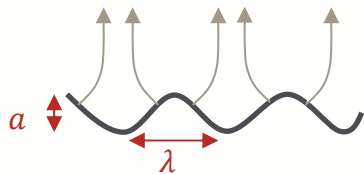
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How can we reduce roughness further?



Impact of Roughness on MTE

Physical roughness



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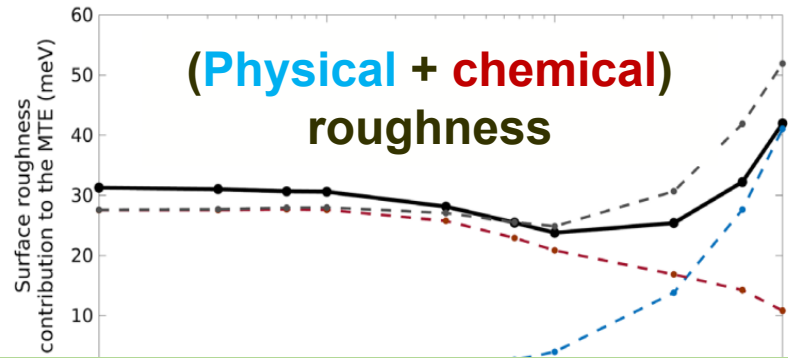
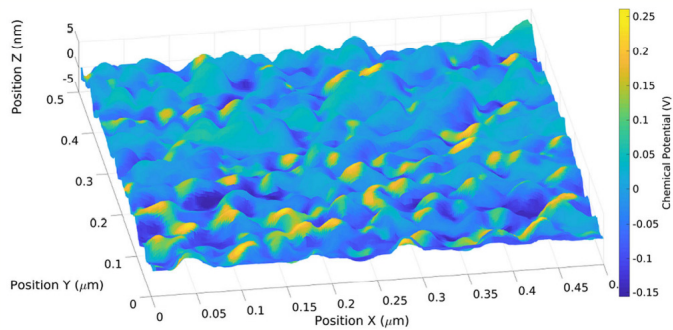
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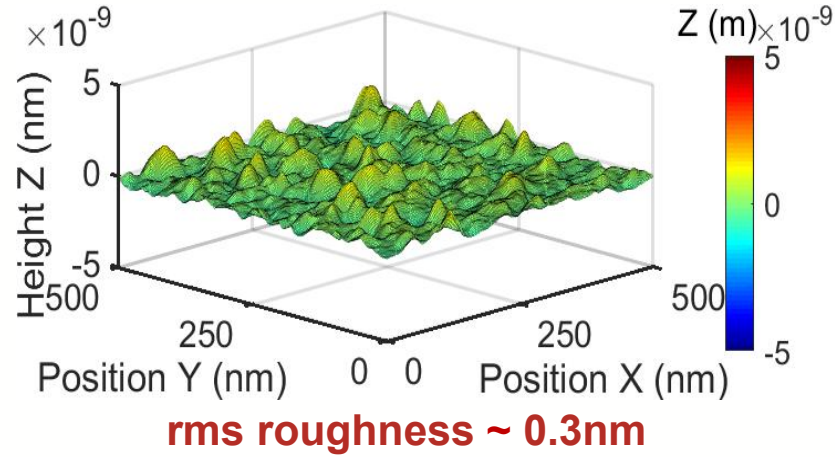


G. Gevorkyan et al. Phys. Rev. ST- Accel and Beams, 21, 093401 (2018)

Grow on lattice-matched substrates?

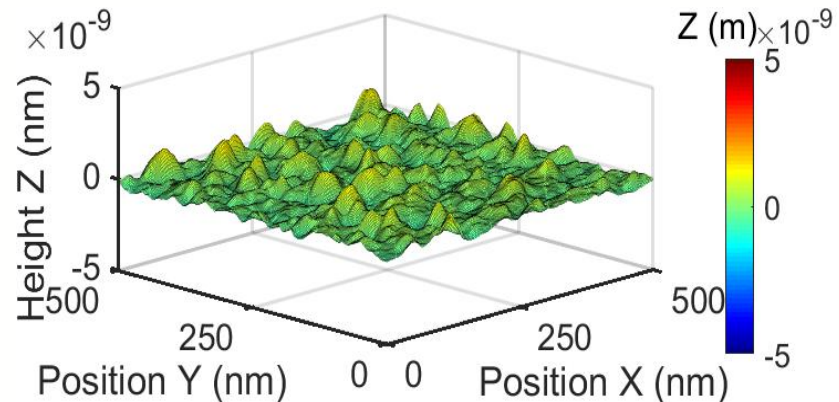


AFM and KPFM images of $\text{Cs}_3\text{Sb}/\text{STO}$ cathodes

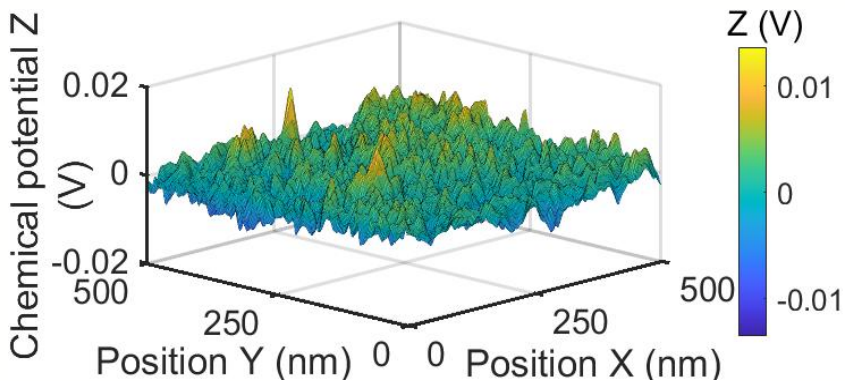




AFM and KPFM images of $\text{Cs}_3\text{Sb}/\text{STO}$ cathodes



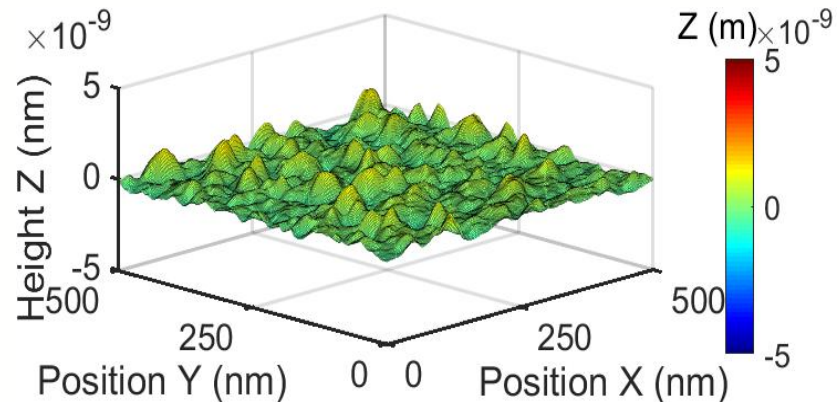
rms roughness $\sim 0.3\text{nm}$



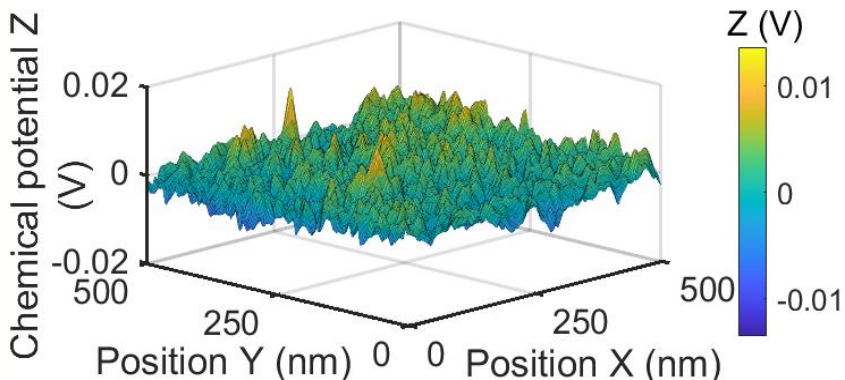
rms roughness $\sim 2.65\text{ mV}$



AFM and KPFM images of $\text{Cs}_3\text{Sb}/\text{STO}$ cathodes



rms roughness $\sim 0.3\text{nm}$

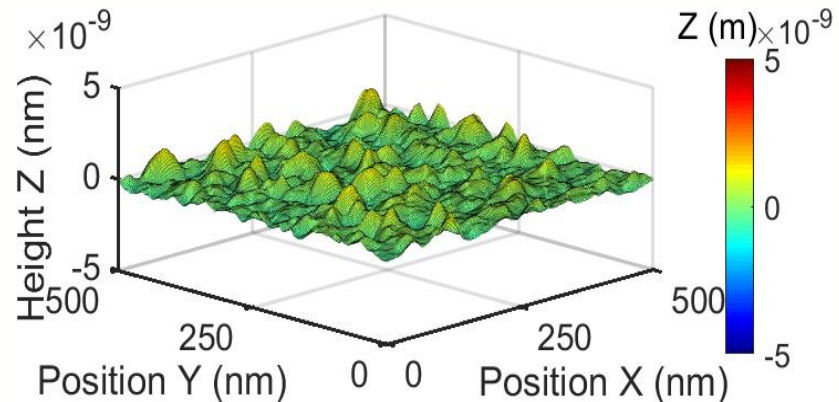


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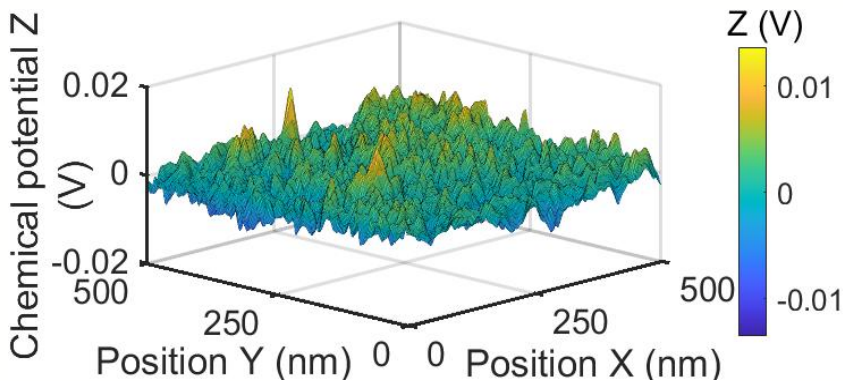
Atomically flat and chemically homogeneous Cs_3Sb cathodes measured on STO.



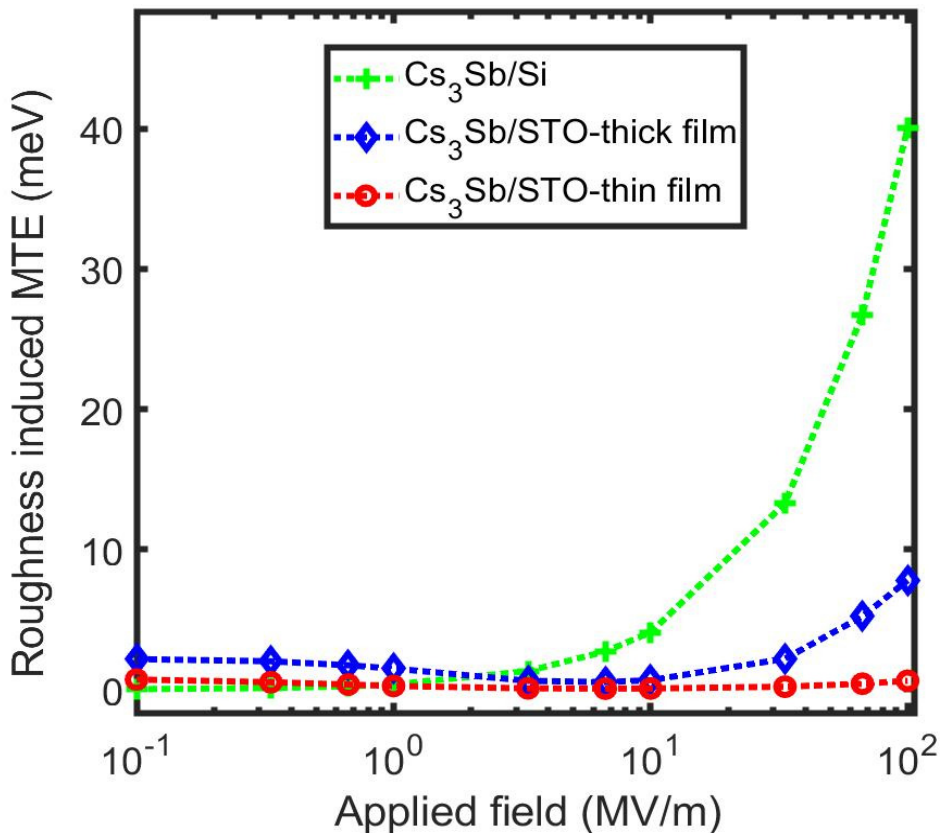
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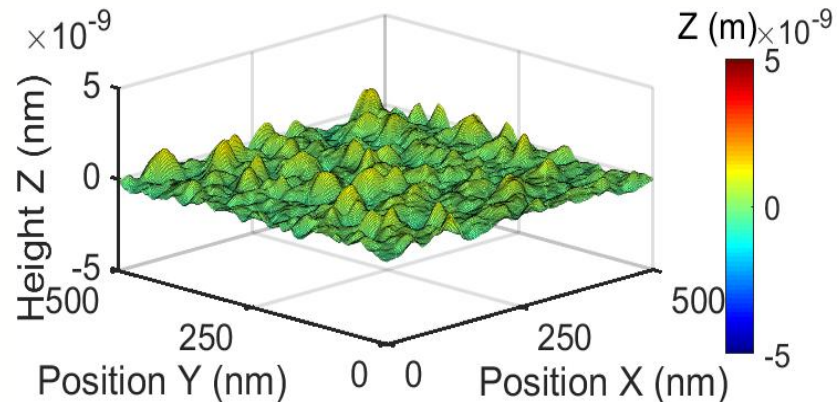


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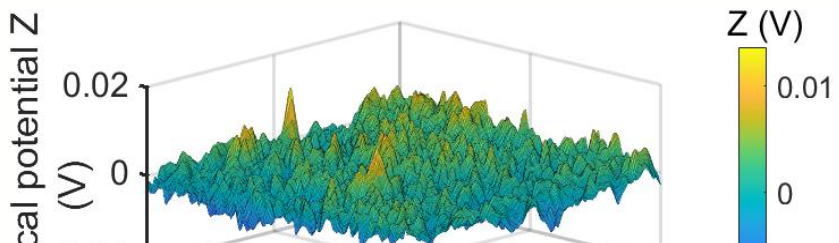




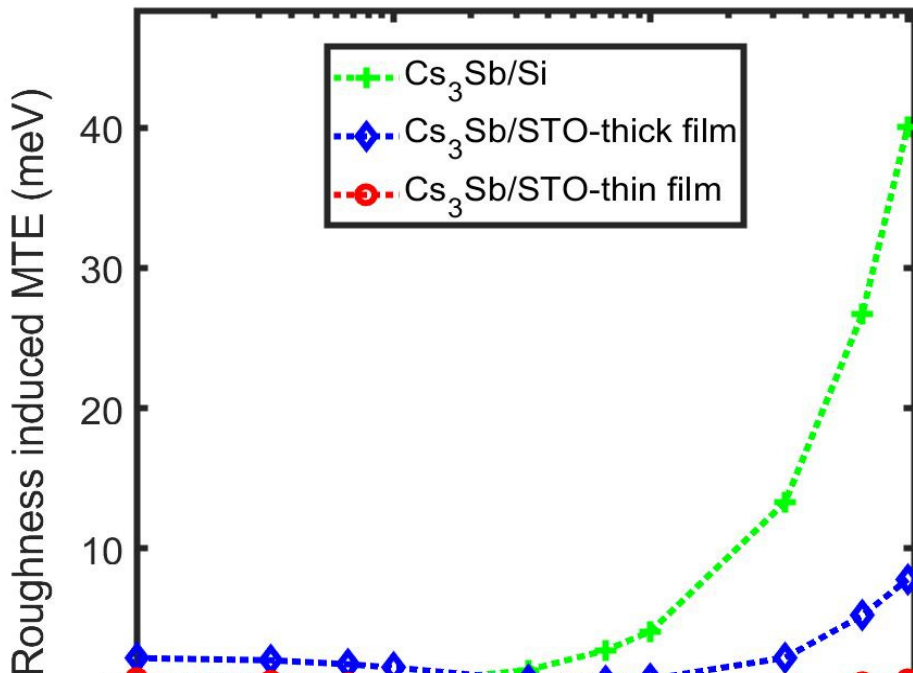
AFM and KPFM images of $\text{Cs}_3\text{Sb}/\text{STO}$ cathodes



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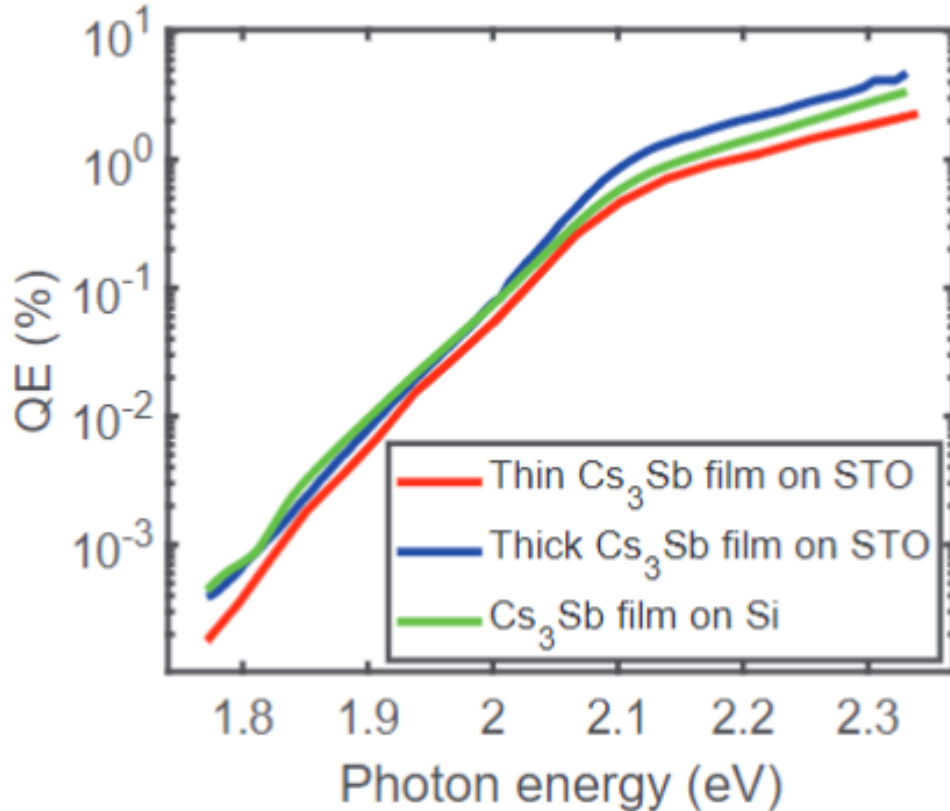
rms roughness $\sim 2.65\text{mV}$



Roughness contribution to MTE inconsequential at all field gradients!



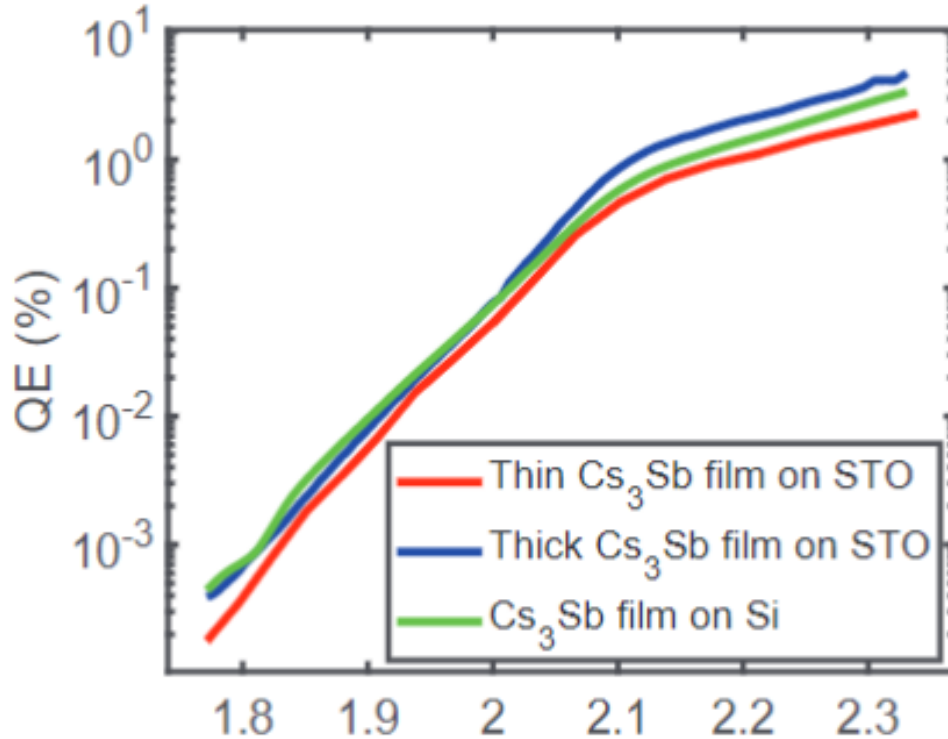
QE Spectral Response



- **Low QE ~ 10⁻² beyond threshold of 2.1 eV.**
- **Higher fluence needed to extract higher charge densities for such low QE , it may lead to MTE degrading effects like non-linear photoemission and laser induced heating...**



QE Spectral Response

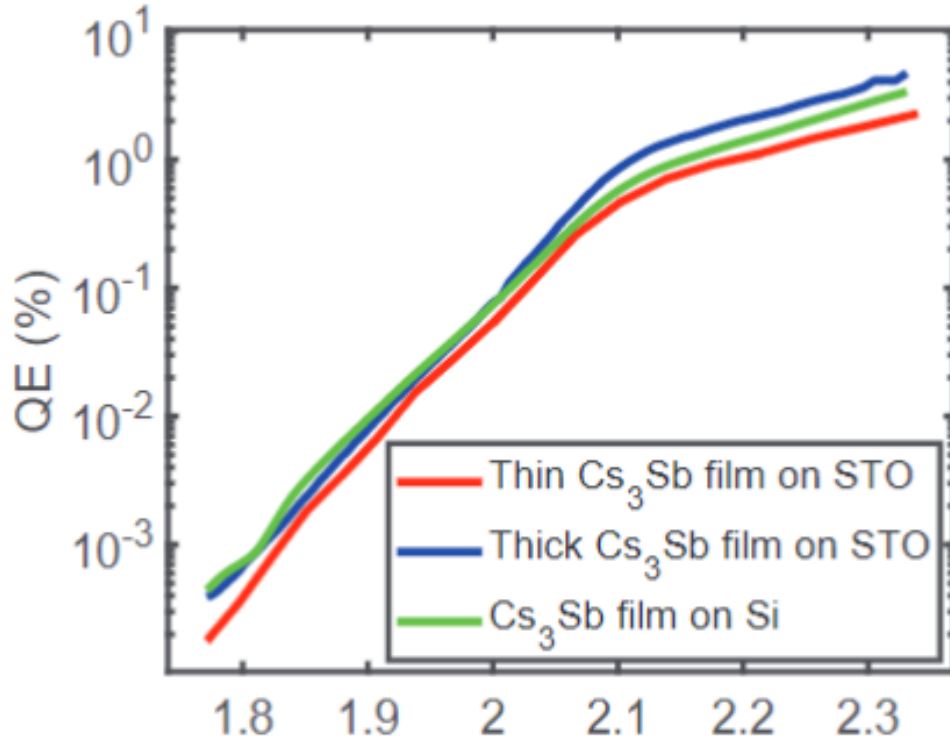


- Low QE $\sim 10^{-2}$ beyond threshold of 2.1 eV.
- Higher fluence needed to extract higher charge densities for such low QE, it may lead to MTE degrading effects like non-linear photoemission and laser induced heating...

Is Epitaxy the way to go?



QE Spectral Response



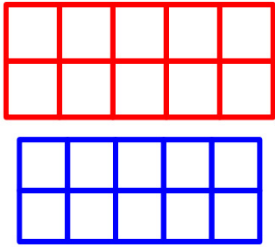
- **Low QE ~ 10⁻² beyond threshold of 2.1 eV.**
- **Higher fluence needed to extract higher charge densities for such low QE, it may lead to MTE degrading effects like non-linear photoemission and laser induced heating...**
- **Use epitaxy to grow ordered heterostructures with fewer defects, which may lead to higher QE.**

Is Epitaxy the way to go?

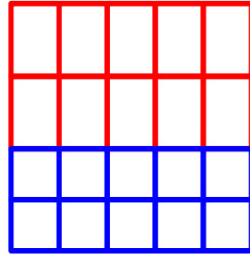


What is Epitaxy?

crystalline layers are formed with one or more well-defined orientations with respect to the crystalline seed layer

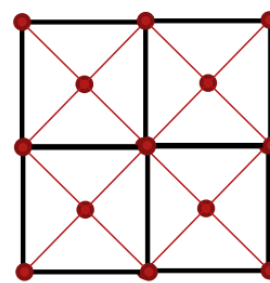


The lattice of the **film** (red) is almost the same as the **substrate** (blue)



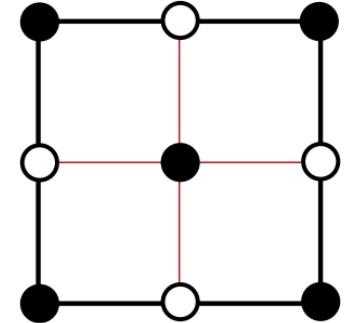
The lattice of the **epitaxial film** (red) distorts to minimize the strain energy where it bonds to the **substrate** (blue)

4 X SiC ($a=0.436$ nm)

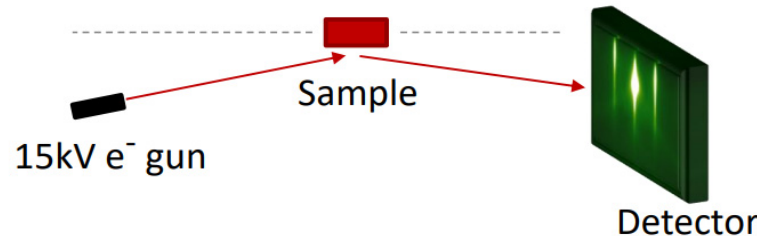


\approx

1 X Cs₃Sb ($a=0.9165$ nm)

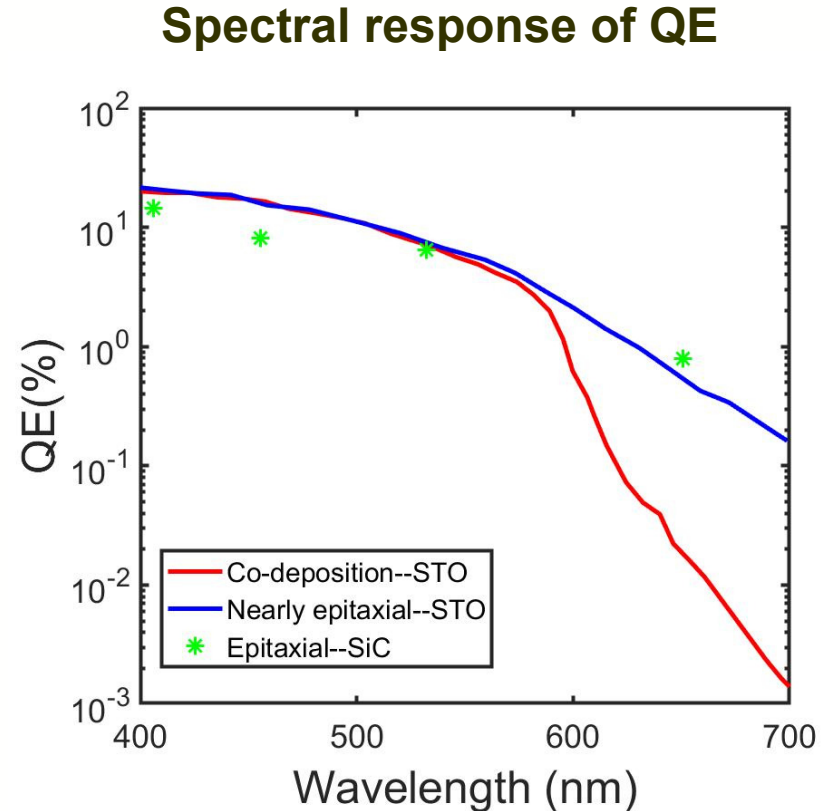
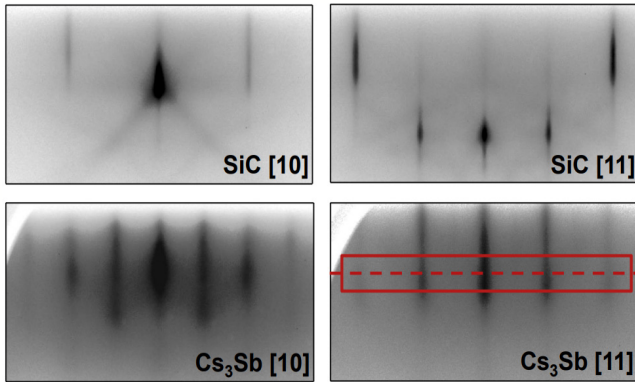
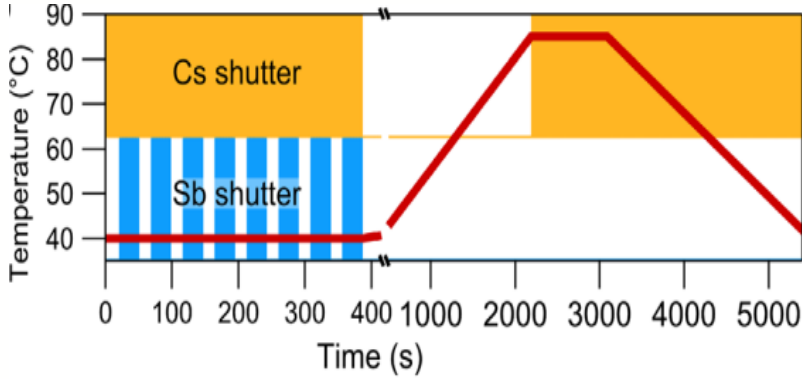


Reflection High Energy Electron Diffraction
(RHEED)





Epitaxial efforts on Cs_3Sb cathodes



C. Parzyck, A. Galdi et. al., Phys. Rev. Lett. 128, 114801 (2022).



Conclusion and Future steps

- Single crystalline Cs_3Sb cathodes are grown epitaxially on lattice-matched substrates.
- ❑ Measure MTE from such cathodes.
- ❑ Optimize epitaxial growth technique of Cs_3Sb cathodes on different substrates to enable controlled doping like in III-V semiconductors.
- ❑ Perform optical characterization of single crystal cathodes.
- ❑ Use epitaxy to grow heterostructures of alkali-antimonides.
- ❑ Enable the use of single crystalline cathodes in electron guns for e.g. the cryocooled DC ASU gun. See next talk by Gevork for more updates!